



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:)	
)	Docket No. LAM2P295
Wen-Ben CHOU et al.)	
)	Examiner: Chen, Kin Chan
Application No. 09/998,858)	
)	Group Art Unit: 1765
Filed: October 31, 2001)	
)	Date: December 16, 2004
For: METHOD AND APPARATUS)	
FOR NITRIDE SPACER ETCH)	
PROCESS IMPLEMENTING -)	
<i>IN SITU</i> INTERFEROMETRY)	
ENDPOINT DETECTION AND)	
NON-INTERFEROMETRY)	
ENDPOINT MONITORING)	

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail addressed to: Commissioner for Patents, P.O. Box 1450, Attn: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on December 16, 2004.

Signed: 
Courtney F. Yadegar

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

This is in response to the Advisory Action mailed on December 1, 2004. The period for response extends to December 16, 2004 with a one-month extension of time. Please enter the following Amendments and remarks in the above-identified patent application:

Amendments to the claims are provided in the Listing of Claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 10 of this paper.